

The **300FA** Automated Failure Analysis system integrates more applications with ergonomic ease of operation. A small footprint, high speed, low cost per feature and serviceability contribute to its' award winning CoO*.

SITEview™ Software Applications Include:

- FA Navigation Software
- User customizable screen
- Automated “manual load” mode for single wafer or wafer piece loading with Deskew
- Defect Review – visit defect sites using defect review file data (any file format)
- Sorting
- Second Optical Inspection
- Image Storage & Retrieval
- GEM/SECS II
- Host Communication – LAN
- UV Microscope Interface



Our commitment to you:

“...We combine the highest quality components with customizable integration to provide true user oriented systems. Tell us your needs, hardware or software, we'll build to your specs...”

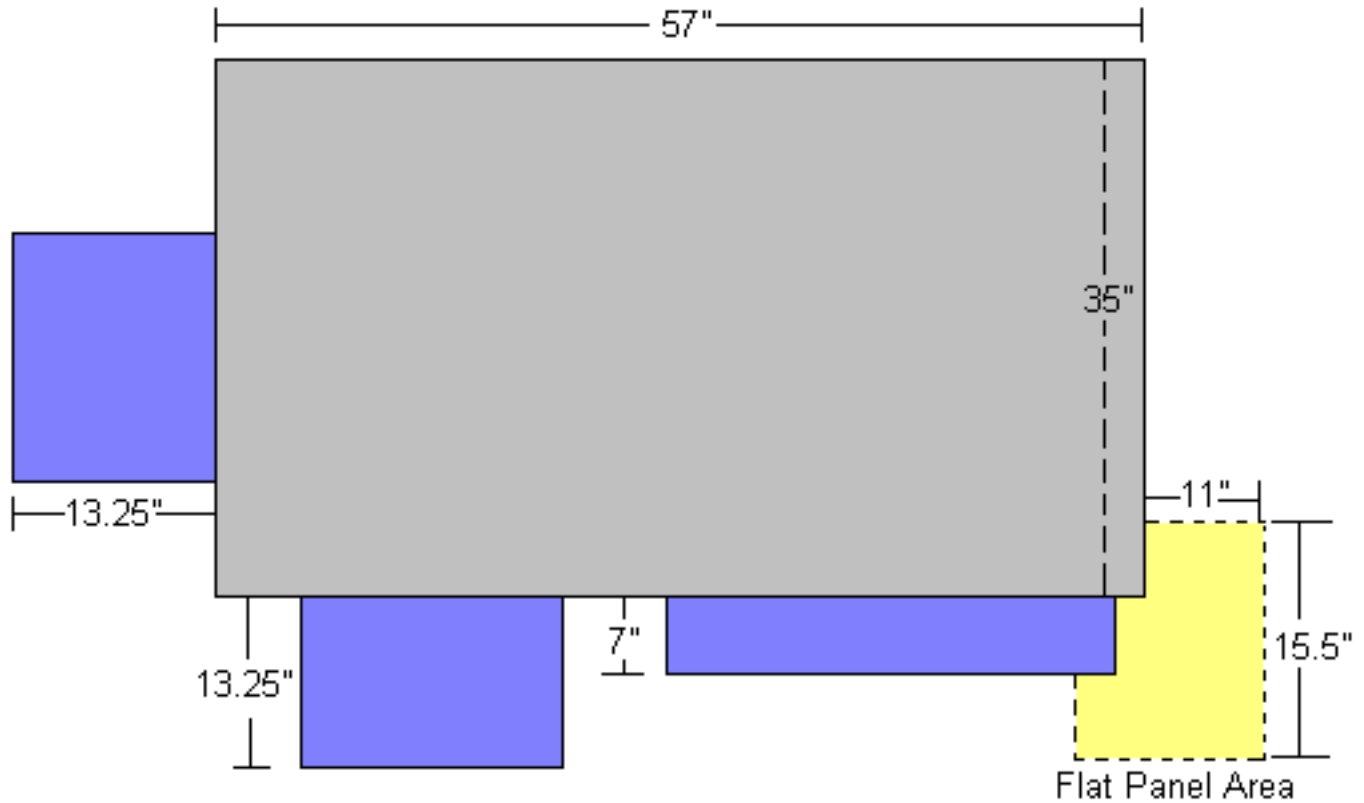
Reiner Fenske - President



Custom Configurations:

- One Bridge Tool for both 200 & 300mm Wafers. Auto wafer size recognition, no calibration
- 1 or 2 Cassette Platforms for manual loading in FA lab
- FOUP indexers available
- OCR – Dual wafer ID recognition
- Alpha-numeric for 200mm & 2D Matrix for 300mm
- **Photonic™** Laser Marker compatible
- Zeiss Optics - BF, DF, DIC, VIS & UV Confocal modes with 80 - 100nm visibility (shown)
- Can integrate all major microscope brands including your existing scopes
- Hi – Precision Stage with embedded 12” x12” Reticle for maximum accuracy
- 20” Hi Res Flat Panel Display
- Active Mini Environment or Passive Enclosure (shown) or open table top design

**Lucent - Vendor of the Year Award
lowest CoO worldwide – Last 2 yrs. held*



- Small footprint
- Mounted on casters and extendable leveling posts for mobility
- 120V/20A Single Phase, One power cord
- Vacuum – 25"/600mm Hg
- No process air or N2
- Configurable for Fab or FA lab
- User customizable enclosure & layout
- Field serviceable robot & peripherals